

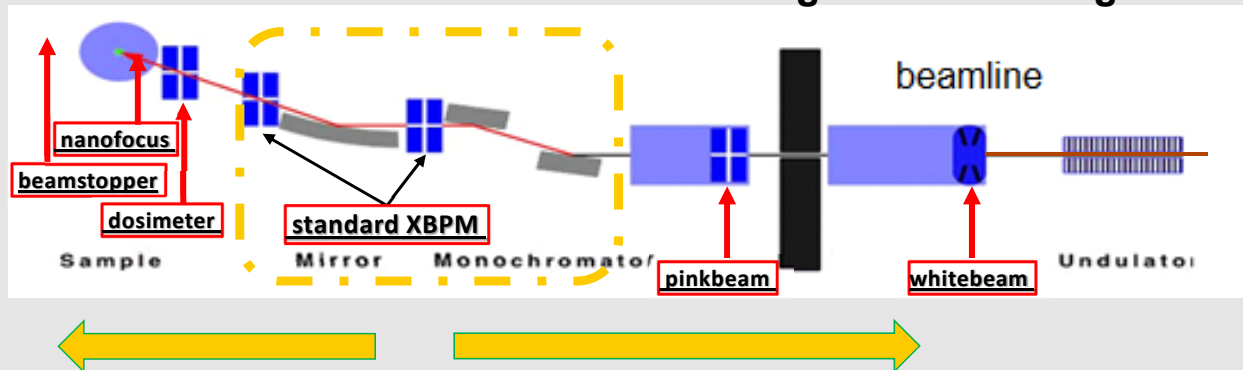


Towards full Silicon Carbide based beam monitoring

Mar Carulla

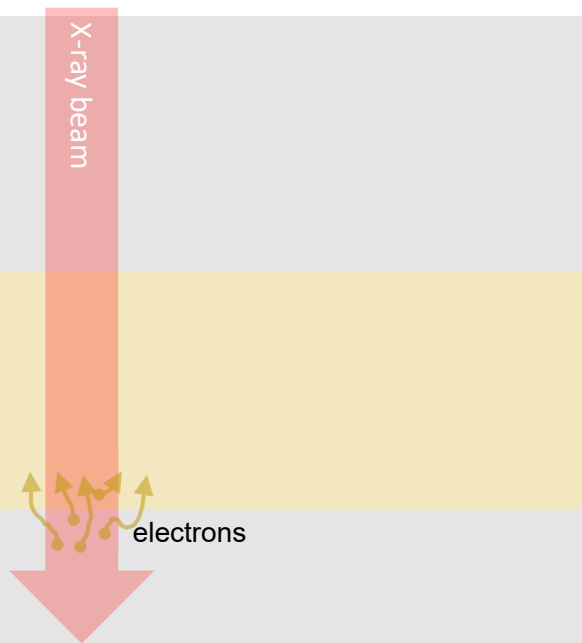
- Overview of beam monitors at SLS
 - Advantages and drawbacks
- State-of-art on solid state monitors for hard Xray
 - SiC vs. Diamond
- Wafer scale processing of SiC XBPM
 - SiC XBPMs produced on 4 inch. wafers
- Current Installations
 - microSAX: After mono, beam stopper and I_0
 - PXI: Pinkbeam
- Future installations
 - nano-imaging
- Extension towards soft-, pink- and white-beams
- Conclusions and outlook

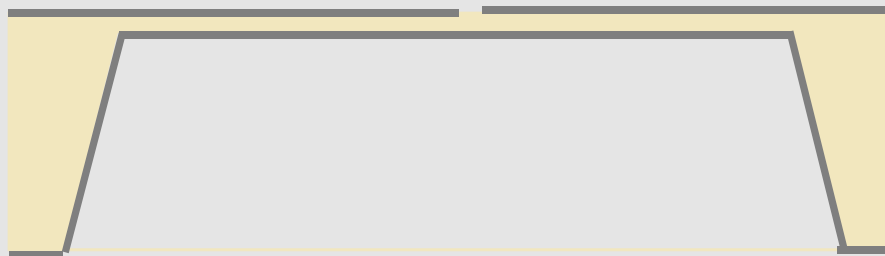
---- Several locations for beam alignment/focusing ----

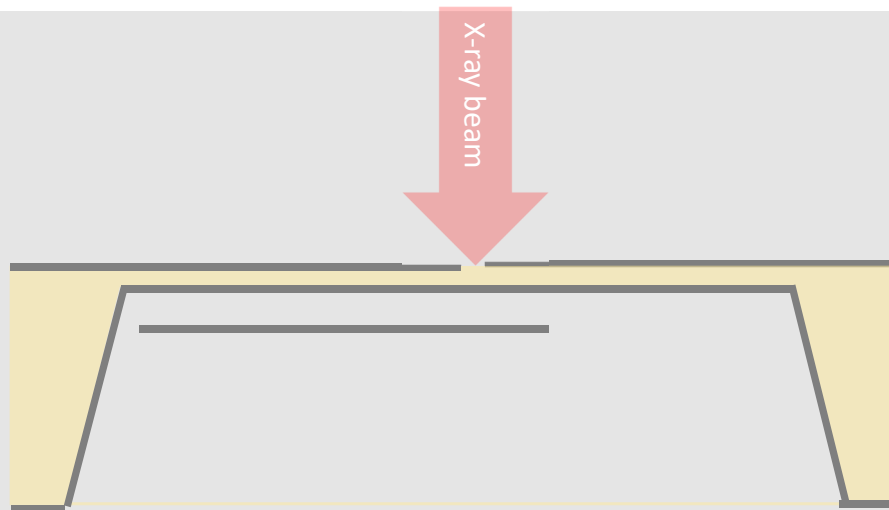


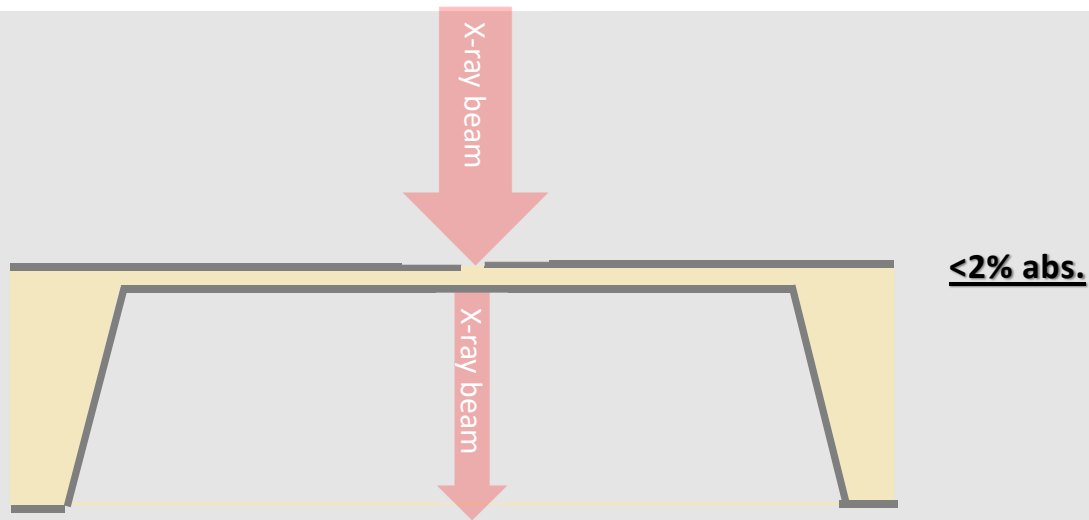
Requirements for in-line X-ray beam monitors

1. Transparency (<2%)
2. Stability over time, i.e. radiation hardness
3. Uniformity (transmittance and photocurrent)
4. Fast response (μs)
5. Easy of fabrication/ Easy of usage / low footprint / vacuum compatibility

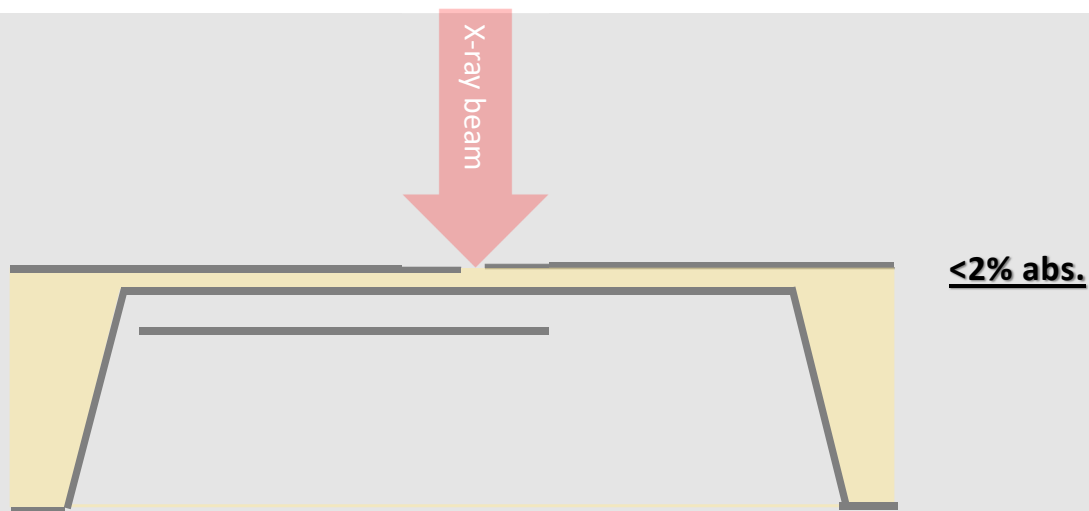








<2% abs.

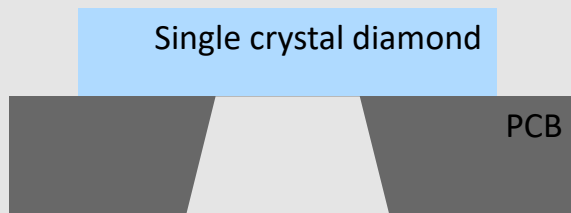


Solid state XBPMs



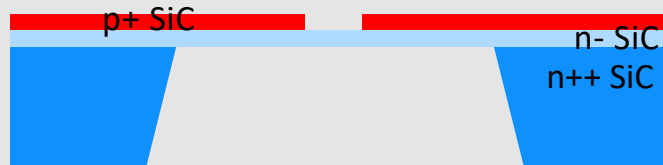
DECTRIS, RIGI
SYDOR

Limited in quality
Poor time response



CIVIDEC
SYDOR

Limited in thickness
Limited in size

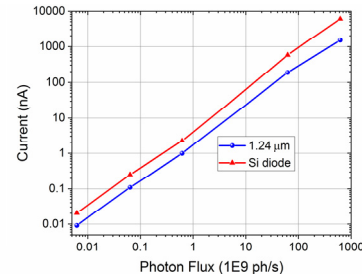
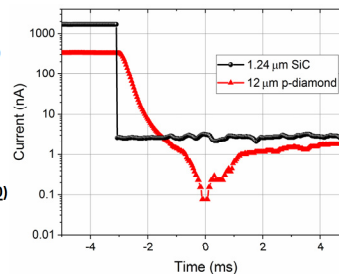
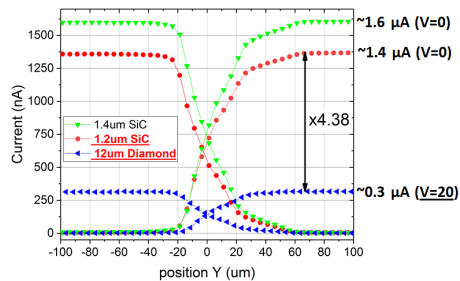
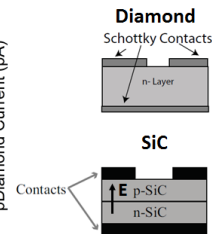
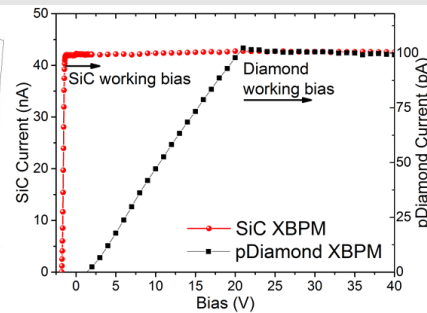
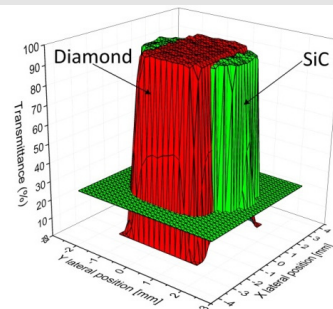


PSI, only!

up to 4-8 inch
down to 1um (0.1)
multiple level mems.

Solid state XBPMs

Comparison with polycrystalline diamond



- SiC XBPM clearly superior to "RIGI" polycrystalline XBPM.
- RIGI now out of the market (No other polycrystalline XBPM vendors)

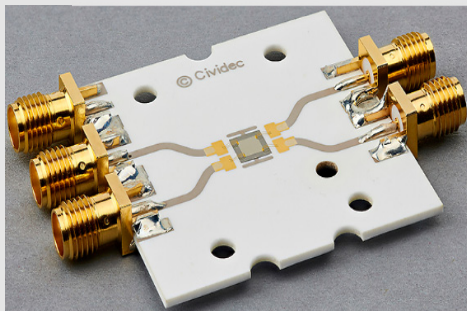
*Nida S. et al "Silicon carbide X-ray beam position monitors for synchrotron applications": J. Synchrotron Rad. 2019. 26, 28-35

<https://doi.org/10.1107/S1600577518014248>

Solid state XBPMs

Comparison with single crystalline diamond

single crystal Diamond



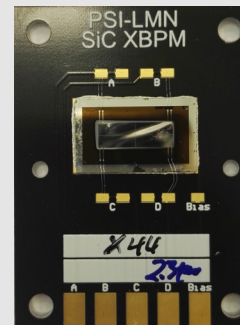
8 order linearity

~ns response

20 μm min. thickness

7 mm² Active Area

SiC XBPM



4 order magnitude linearity*

~ μs response*

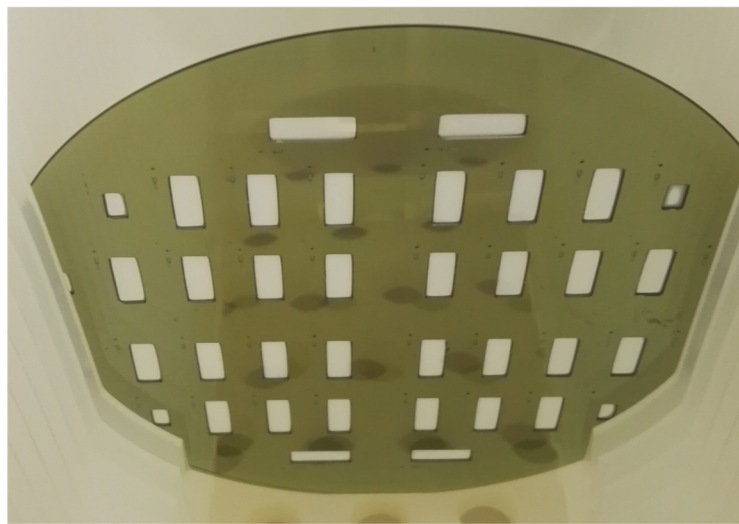
2 μm min. thickness

36 mm² (72 mm²) Active Area (x5)

* limited by measurement setup

** considering different att. length

Wafer scale processing

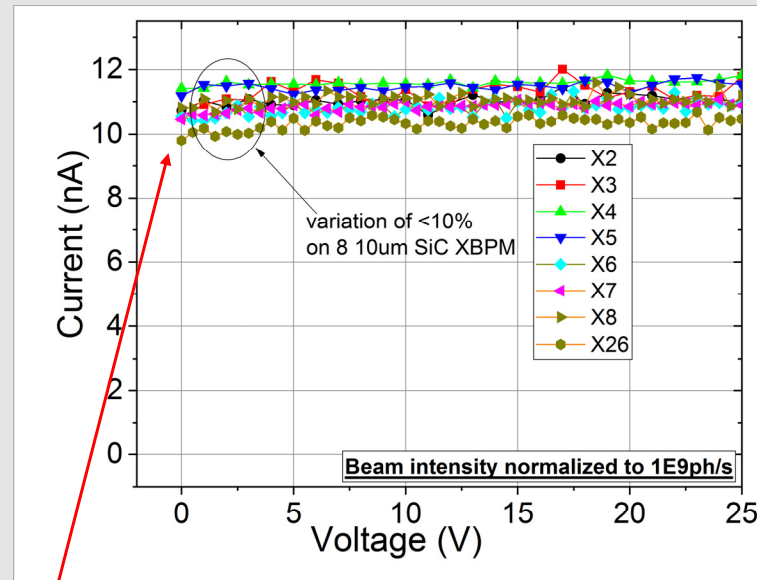
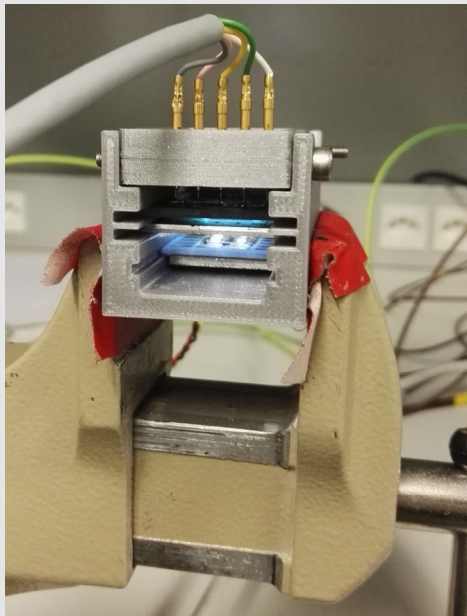


- 50 devices per wafer
- Wafer processing lasts 2 weeks

Wafer scale processing of SiC

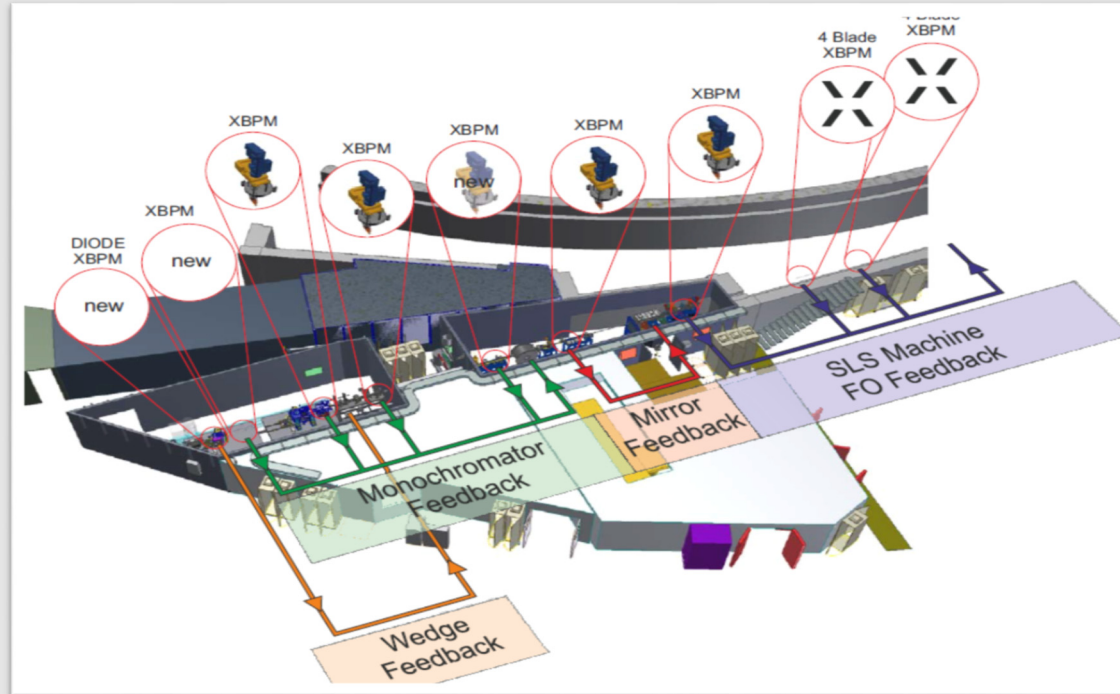
Stability

- Fully automated UV (325nm) LED based screening system



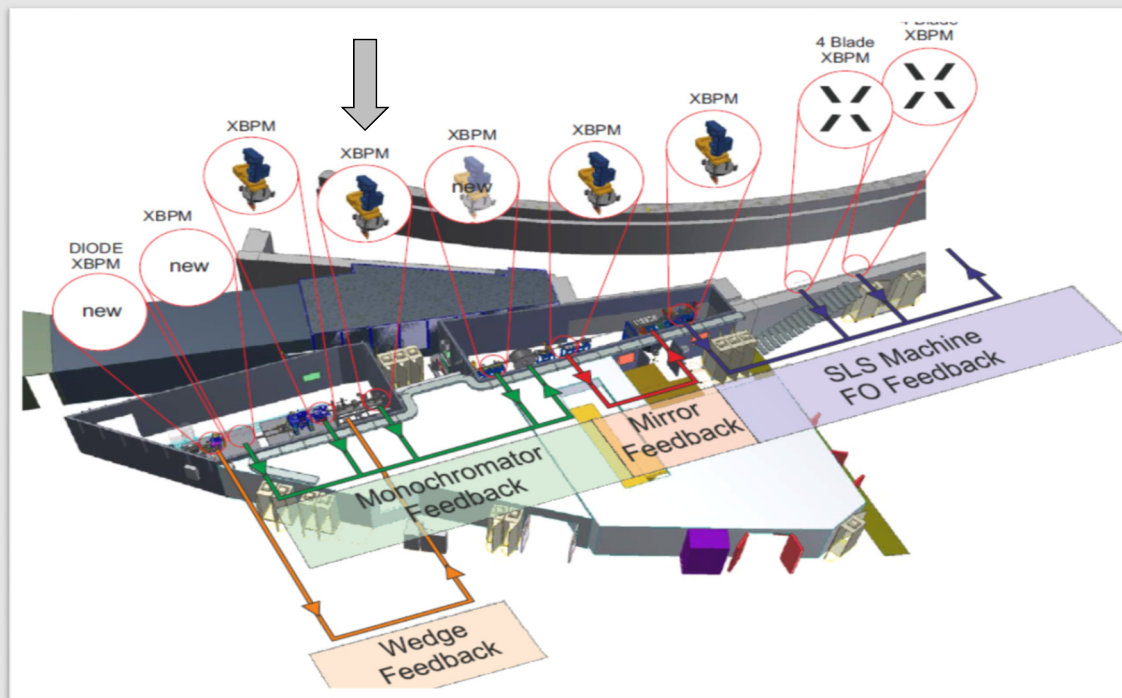
Operation at 0V

Current installations at microXAS



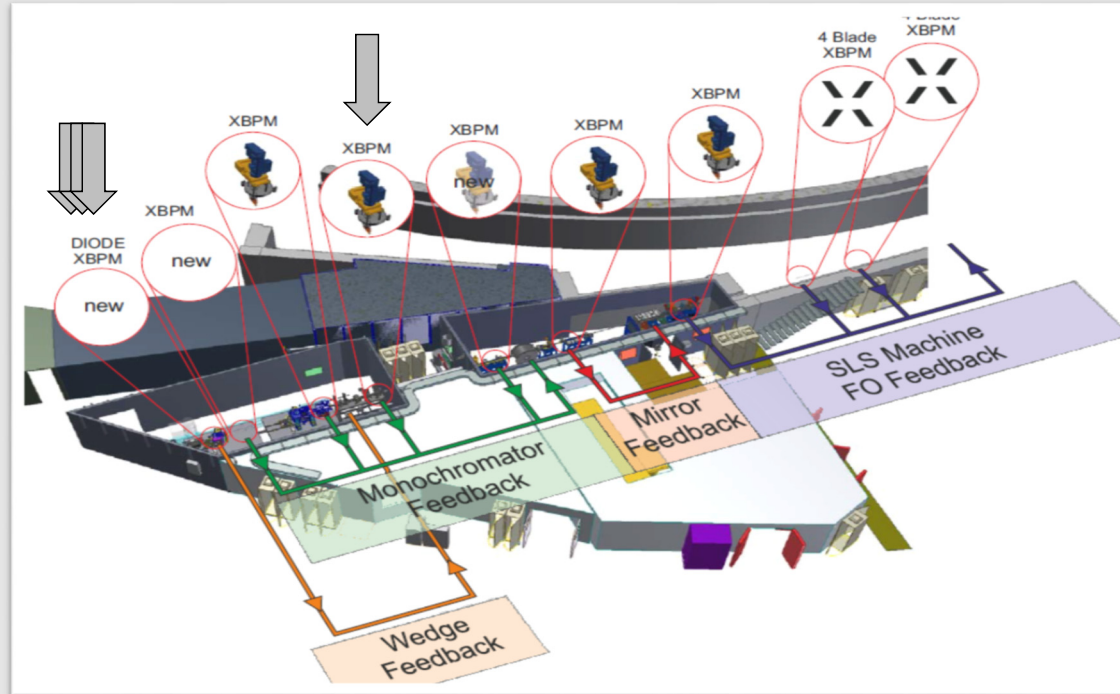
- **Currently installed @ microXAS: 3 XBPMs (after mono, IO, and beam-stopper)**

Current installations at microXAS



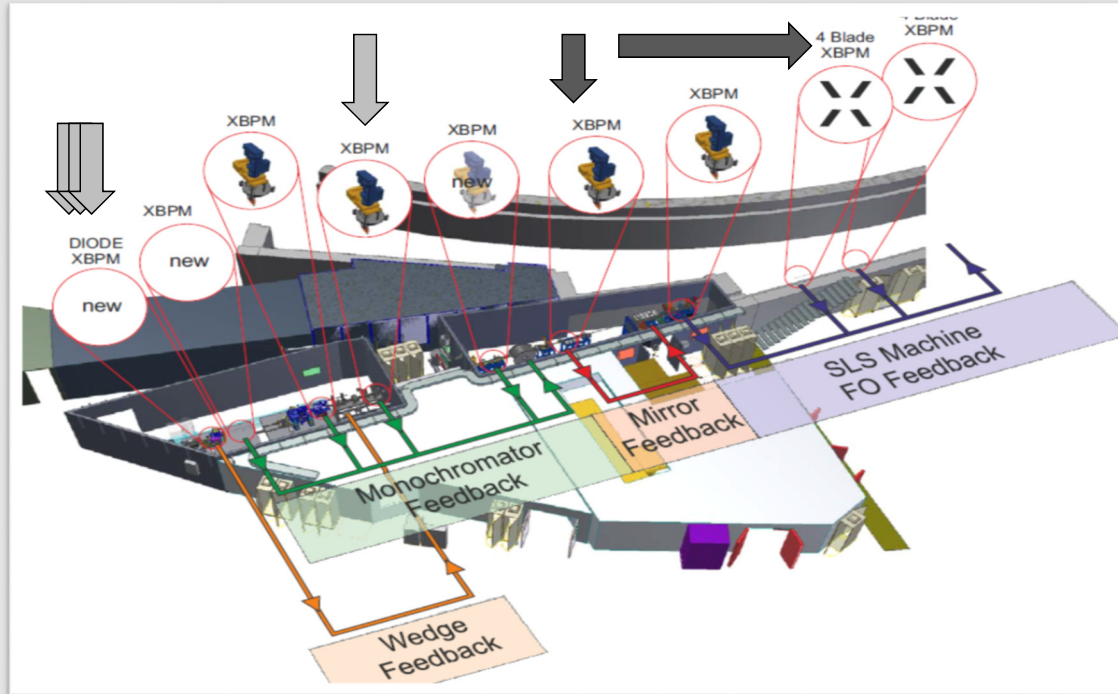
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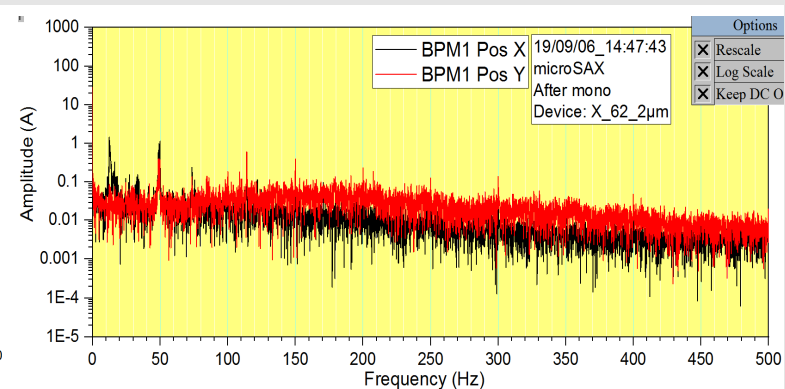
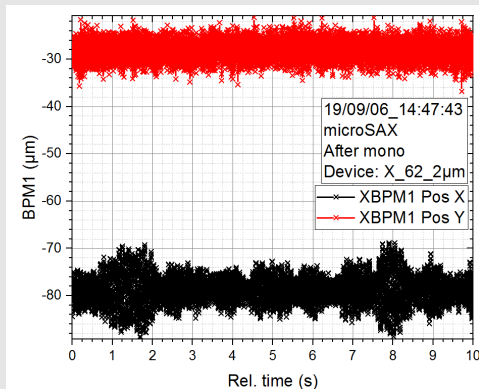
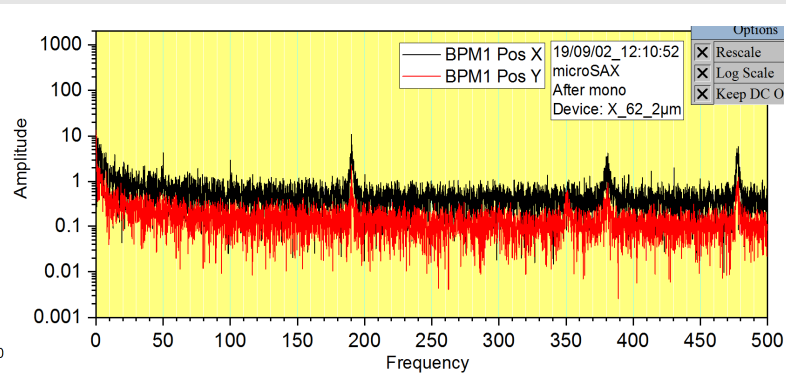
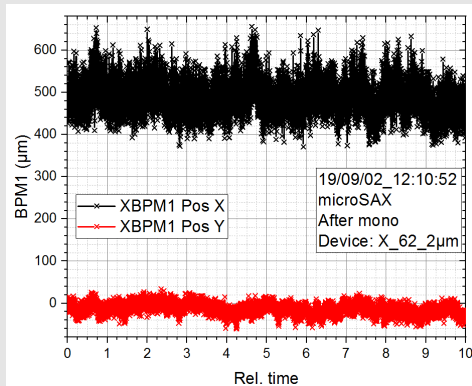
Current installations at microXAS



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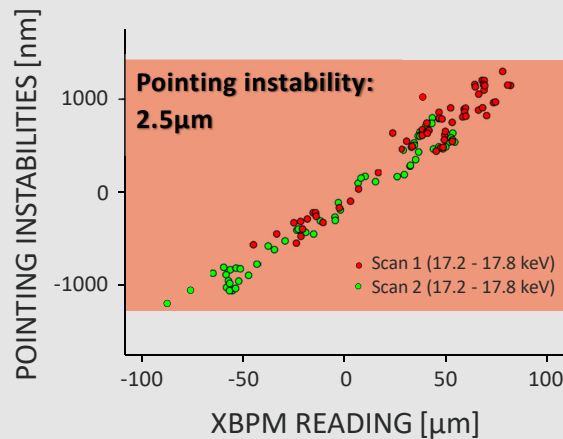
Current installations at microXAS

-first implemented SiC XBPM

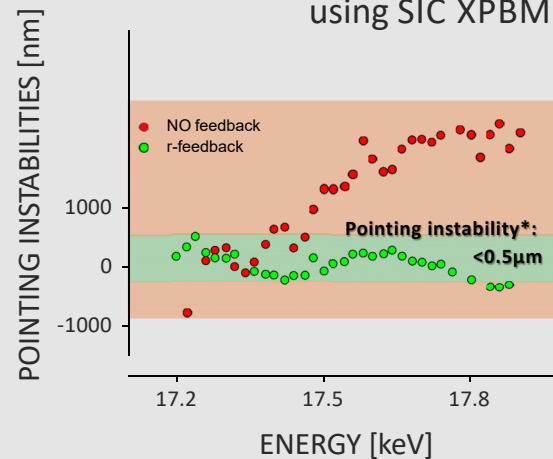


Current installations at microXAS

-first implemented SiC XBPM



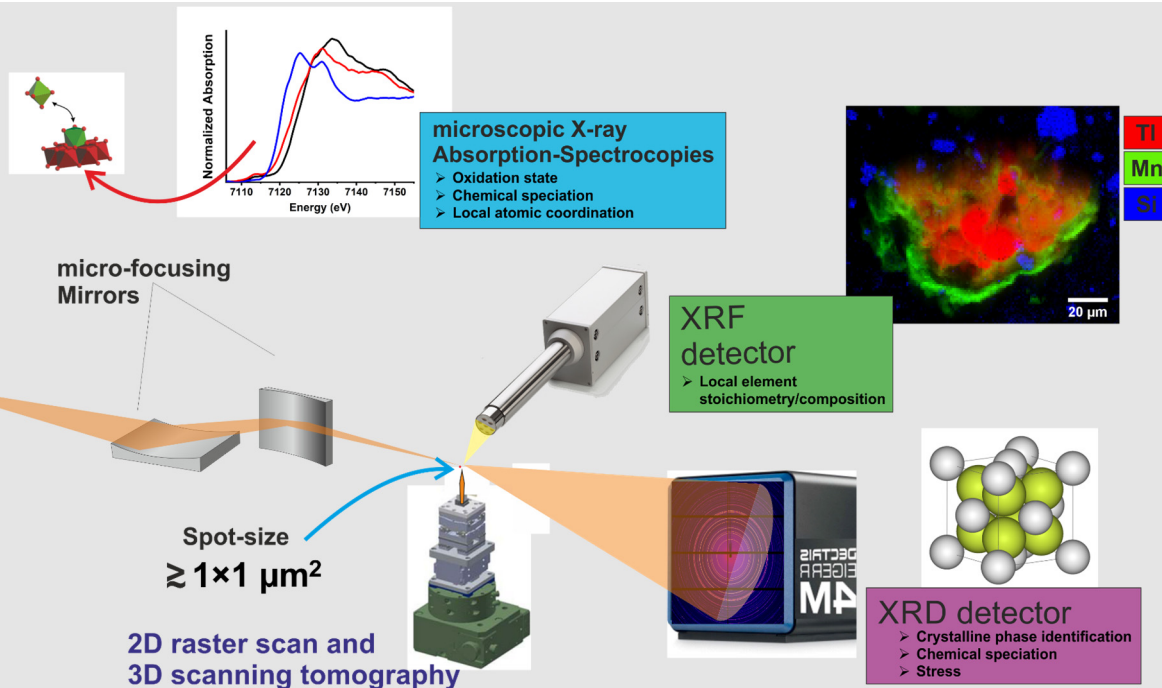
Improvement based on
rudimentary feedback system
using SiC XPBM



*sigma: <400nm

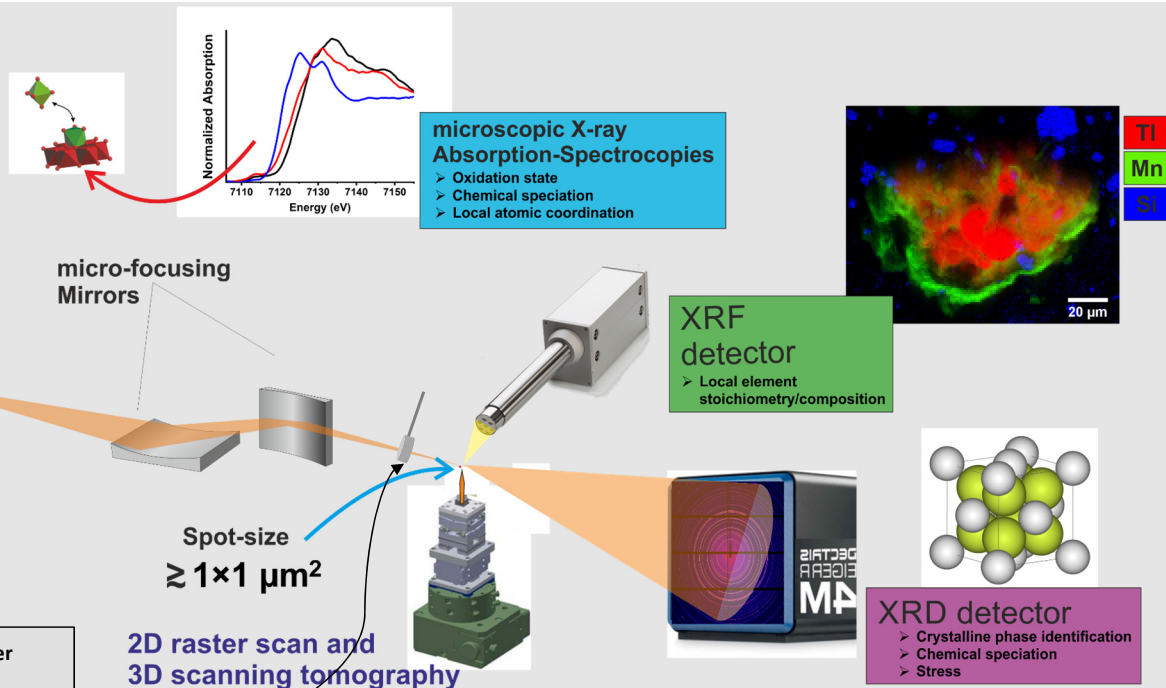
Current installations at microXAS

-Beam stopper diode (no transmittance mode)



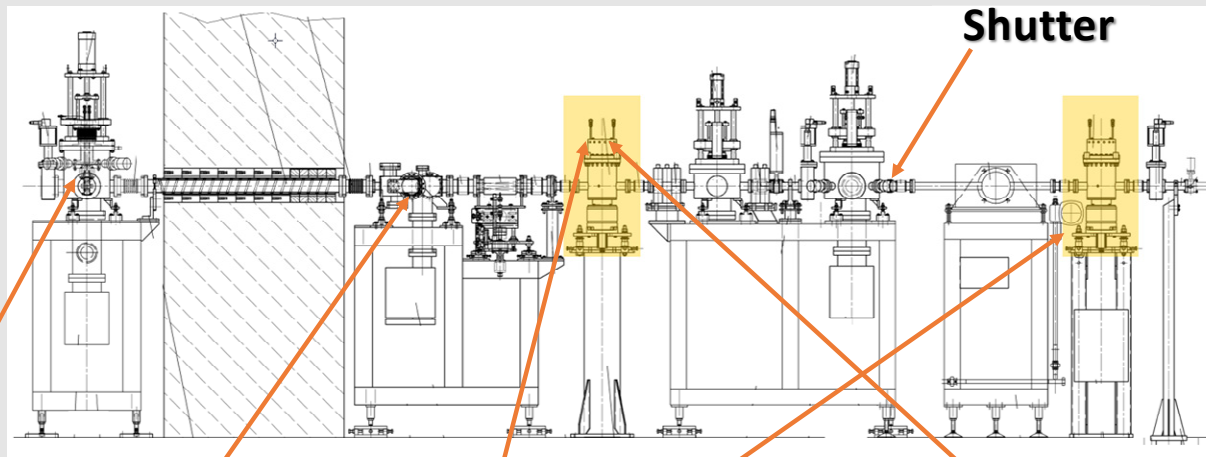
Current installations at microXAS

-Beam stopper diode (no transmittance mode)



Courtesy: Dario Sanchez

Current installations at PXI (pinkbeam)



Pinkbeam 80µm C window

800W (36W)

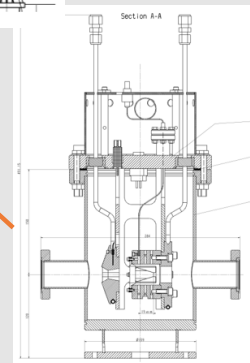
<1% at 12.4keV

currently on 2µm
device installed at PXI

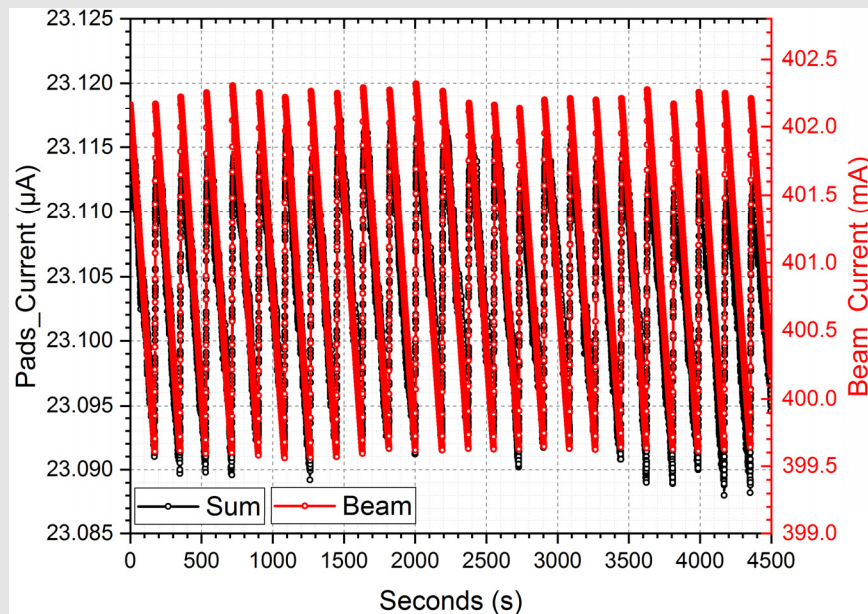
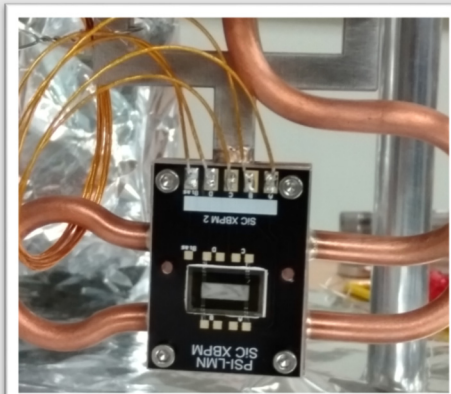
Whitebeams

2kW (5.2mm gap)

Shutter

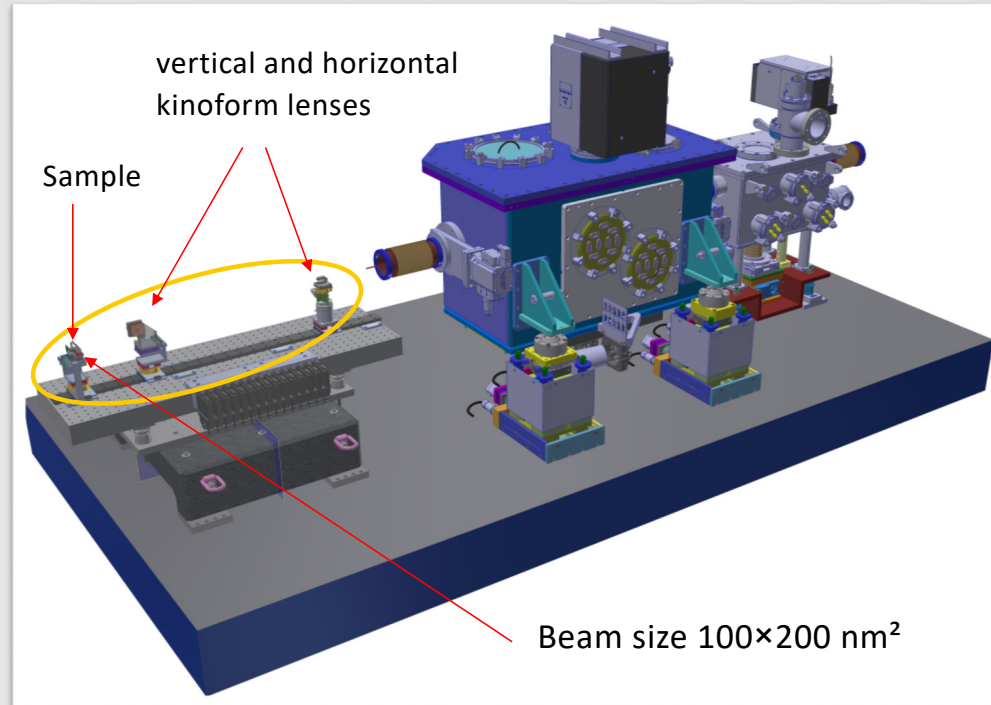


Current installations at PXI (pinkbeam)

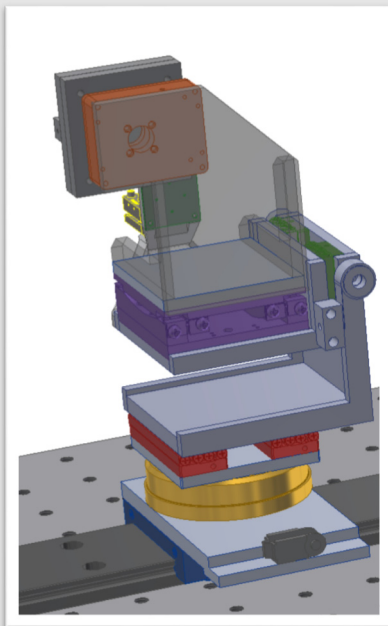


- 2 μm XBPM was installed 1 month ago at PXI pinkbeam (after diamond window).
- The measured current is several order of magnitude lower than the expected one.

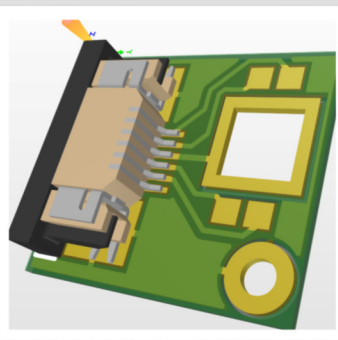
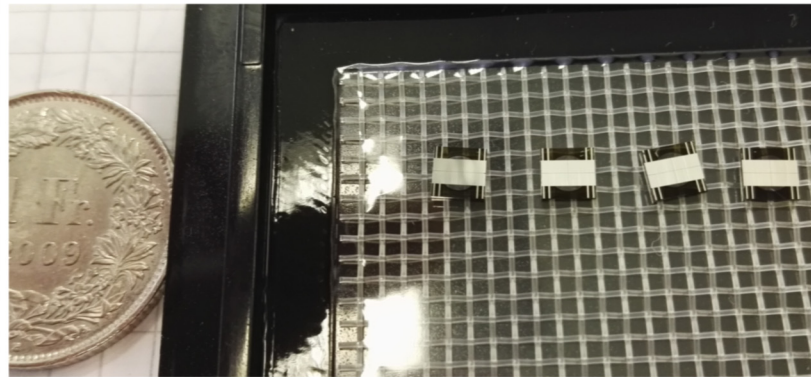
Future installations: Near sample monitoring -3 compact XBPM for nano-imaging



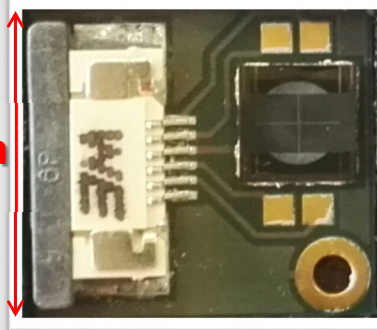
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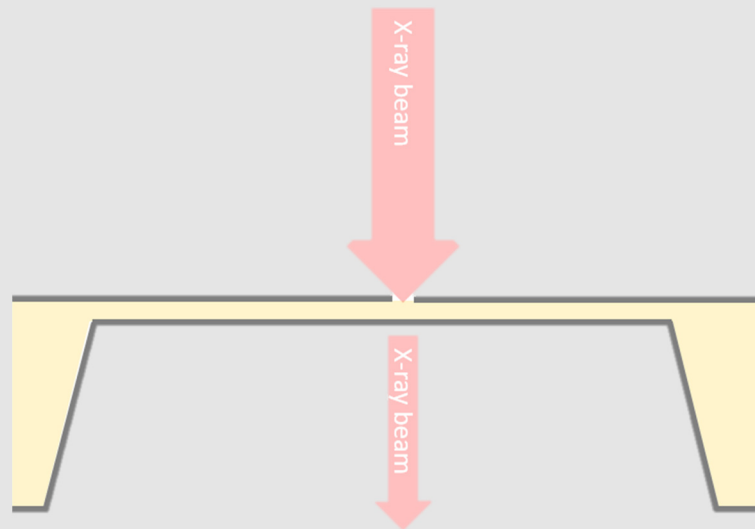


Installation expected
Dec. – Nov. this year

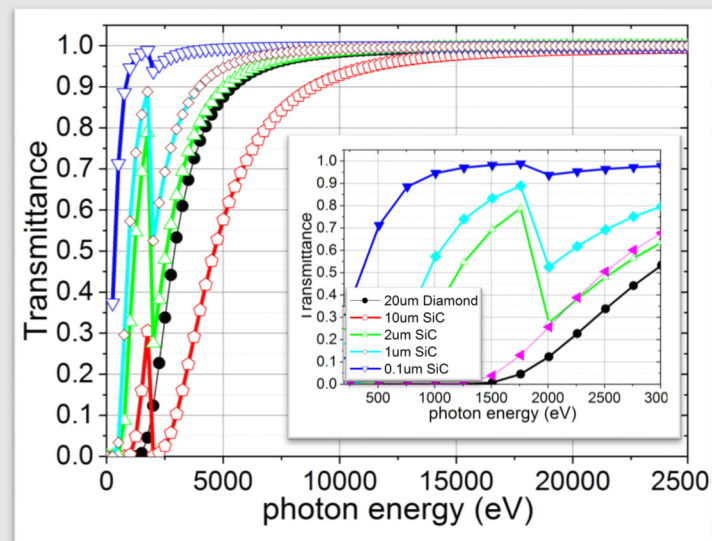


1cm

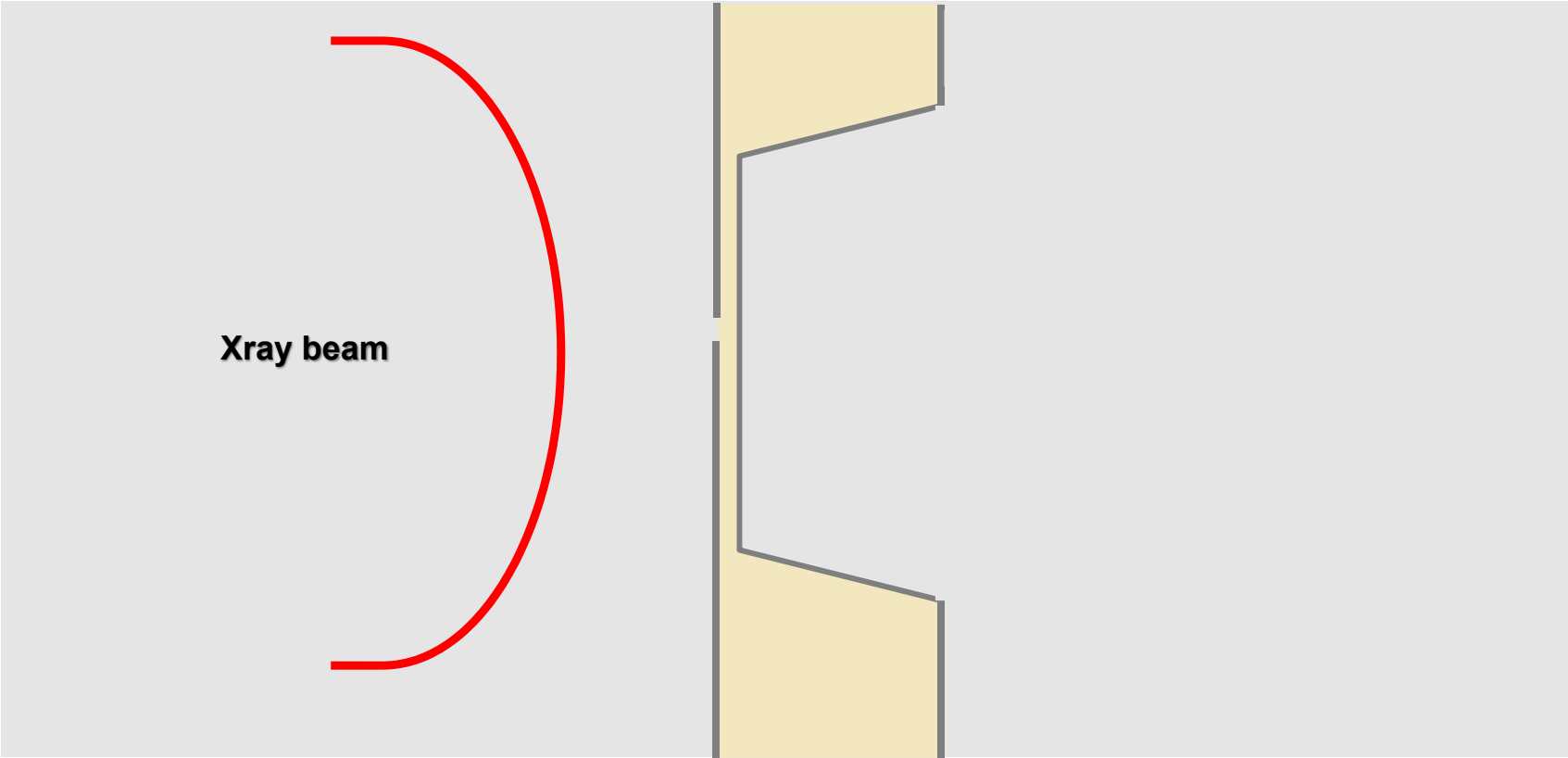


**Limitation of thin membranes as XBPM:**

- 1) high abs. for soft x-ray
- 2) thermal issues for white beams



Future extensions: white x-ray beams



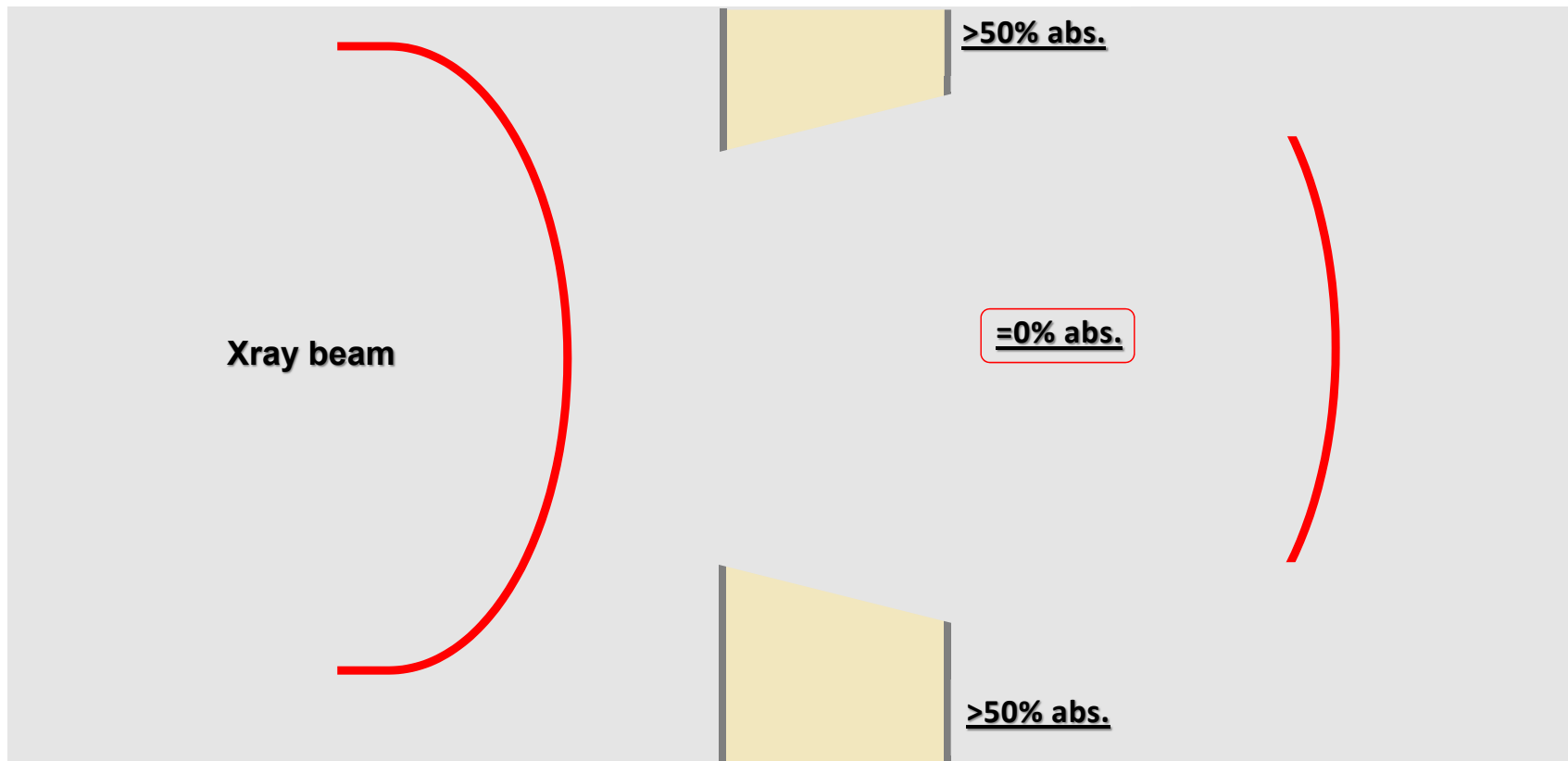
Xray beam

Future extensions: white x-ray beams

Xray beam

=0% abs.

Future extensions: white x-ray beams

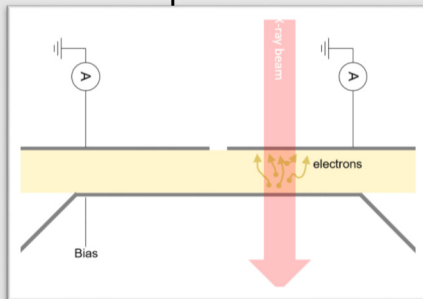


Future extensions:

Why better than blades

Why valuable "functionalized" pin-holes

semiconductor based
internal photoemission

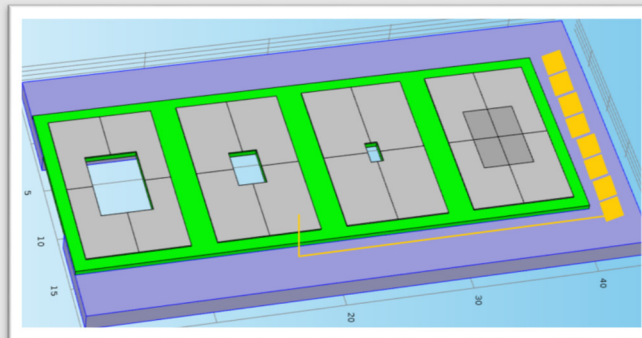
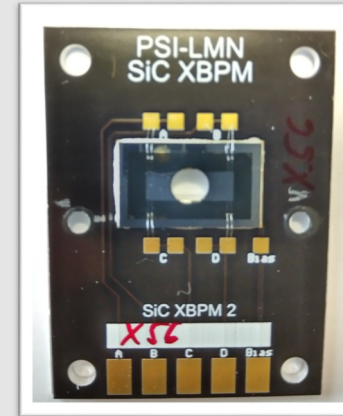
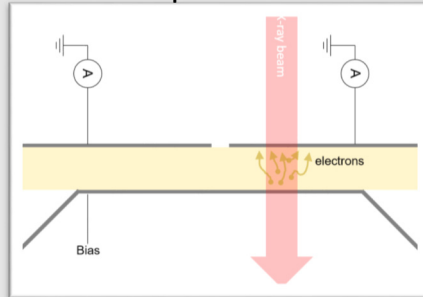


Future extensions:

Why better than blades

Why valuable "functionalized" pin-holes

semiconductor based
internal photoemission



array of 4 devices

1. -- full membrane, -- "high res."
2. -- "small pin-hole": $2.0 \times 1.0 \text{ mm}^2$
3. -- "blade opening": $3.4 \times 2.2 \text{ mm}^2$
4. -- "large pin-hole": $6.0 \times 4.0 \text{ mm}^2$

Conclusions:

- 4H-SiC XBPM: transparency, linearity, signal strength.
- They can be operated at 0V.
- 2 μm 4H-SiC XBPM devices were installed at microSAX (after monochromator) and PXI (pinkbeam) beamlines at PSI.
- PXI (pinkbeam): current several orders of magnitude lower than expected.
- microSAX (after monochromator): 20 $\times$ improvement on beam stability over energy scans

Future work:

- Installation of Compact XBPMs for nano-imaging
- Blade monitors (whitebeam)
- 0.1 μm thin XBPM for soft X-rays

Acknowledgments

- Hans Sigg
- Oliver Bunk
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- Mario Birri
- Beat Meyer
- ALL LMN
- pBPM working group

